

Quantifying Acoustic Intermodulation Distortion from a Dual-Frequency (3+5 MHz) Megasonic Cleaning System

Nicolas Candia*^a, Ralf Emberger^b, Ashish Shivaji Salunke^c, Baorui Yang^c, Petrie Yam^a

^a Onda Corporation, 1290 Hammerwood Ave., Sunnyvale, CA 94089, USA

^b SONOSYS Ultraschallsysteme GmbH, Daimlerstraße 6, 75305 Neuenburg, Germany

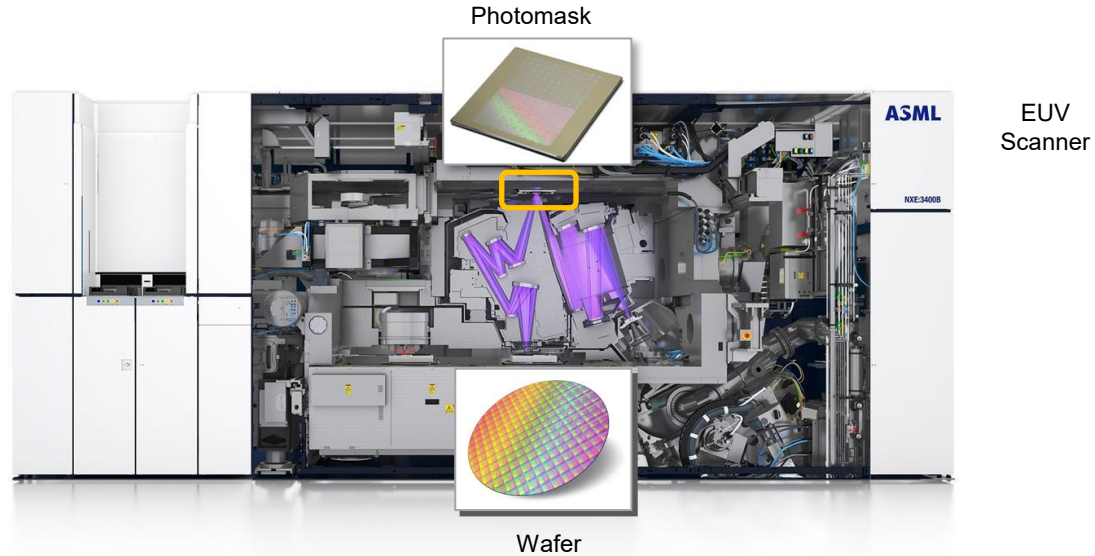
^c Micron Technology, Inc., Boise, Idaho, USA

September 9, 2026



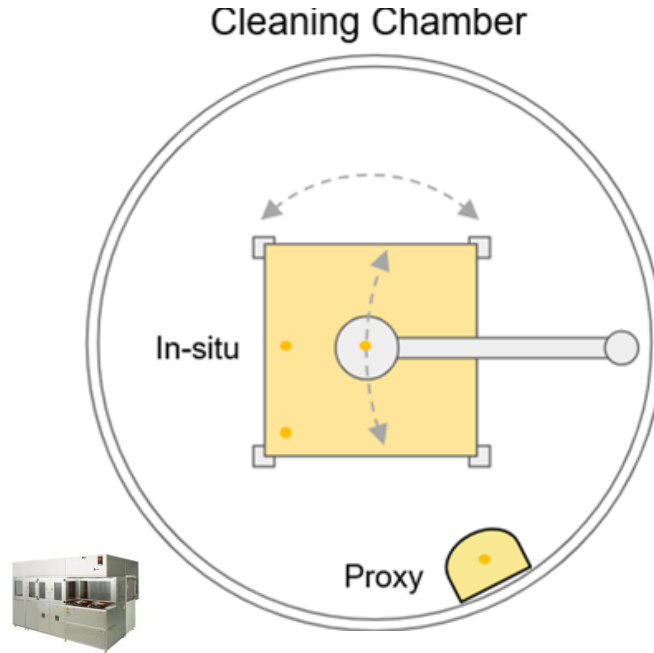
SPIE BACUS Monterey, CA

Advanced Photolithography



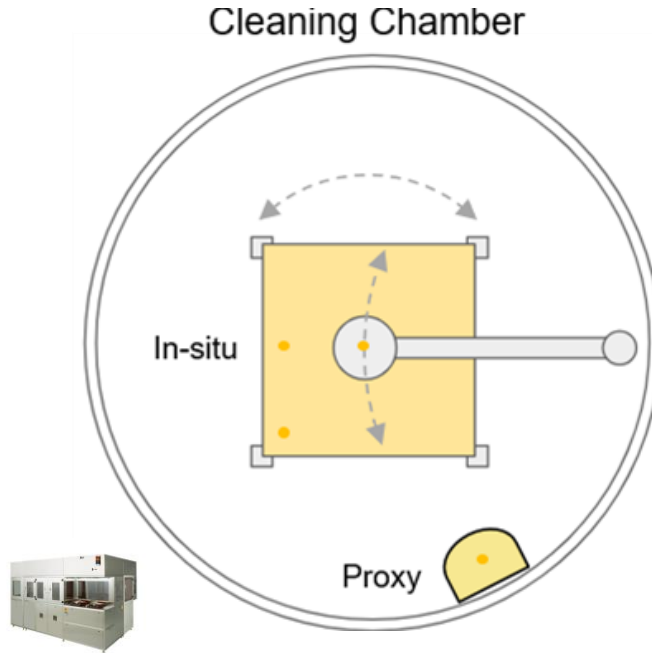
***Advanced mask cleaning processes (193i and EUV)
demand zero-defects***

Photomask Cleaning Systems



Transducers apply “Megasonic” pressure to mask surface to remove particles

Photomask Cleaning Systems

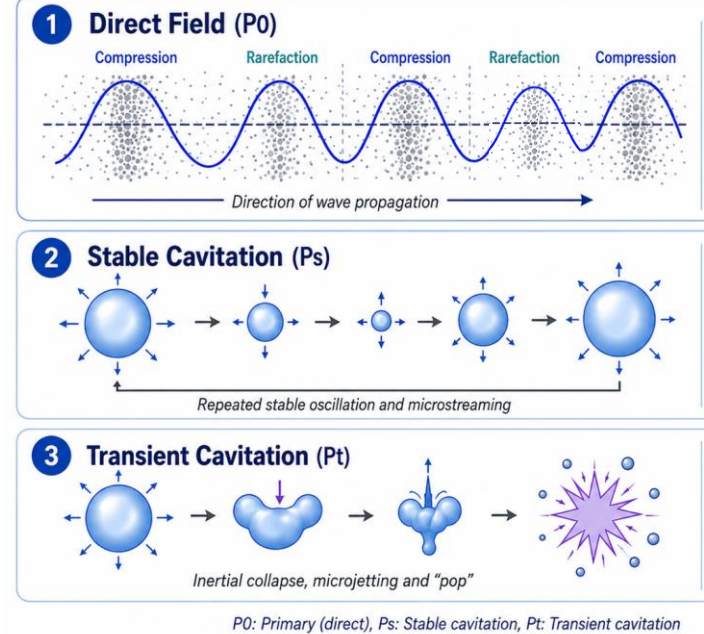
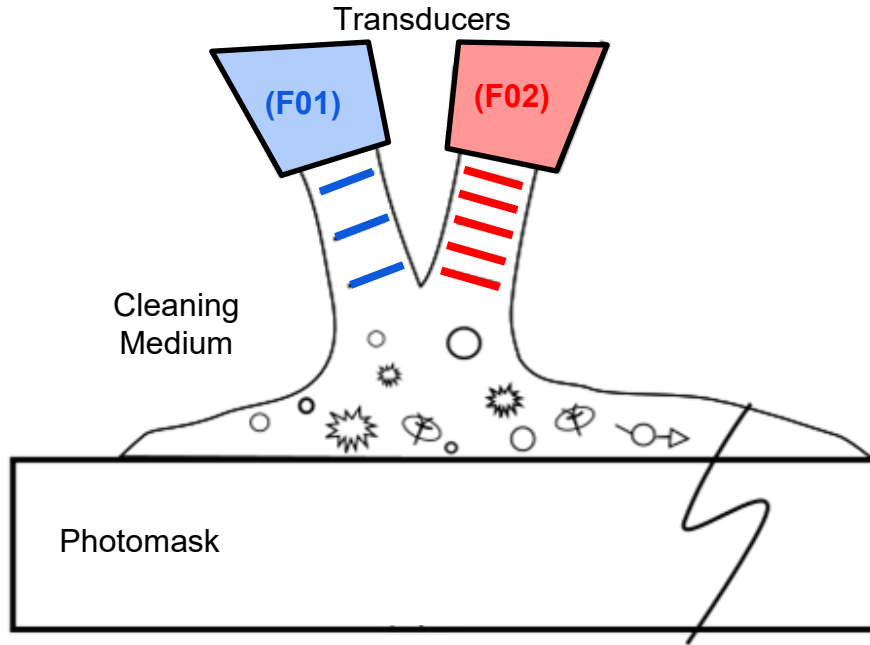


Sonosys
3 + 5 MHz



Transducers apply “Megasonic” pressure to mask surface to remove particles

“Mechanical Agitation” from Ultrasound

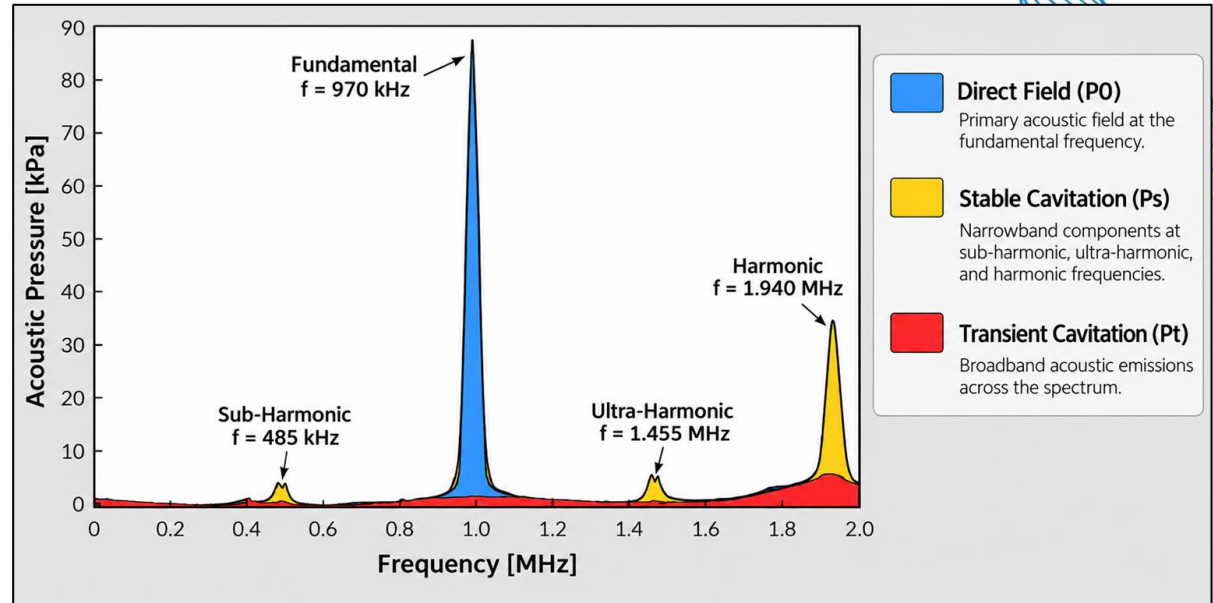


Anatomy of Acoustic Spectrum (Single Frequency)

ONDA MCT-20x0
Acoustic Cavitation Meter

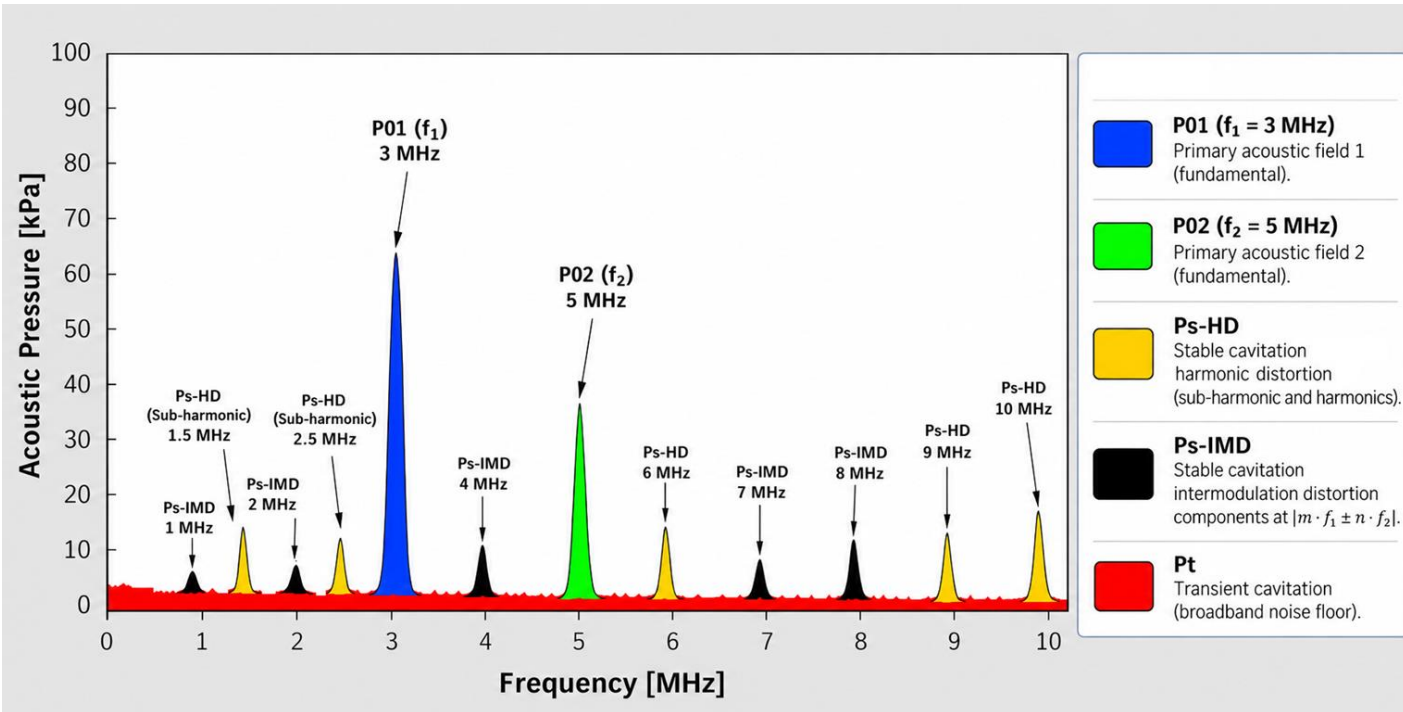


ONDA CMS-5000
Cavitation Monitoring Sensor



Different pressure components contribute to cleaning and damage

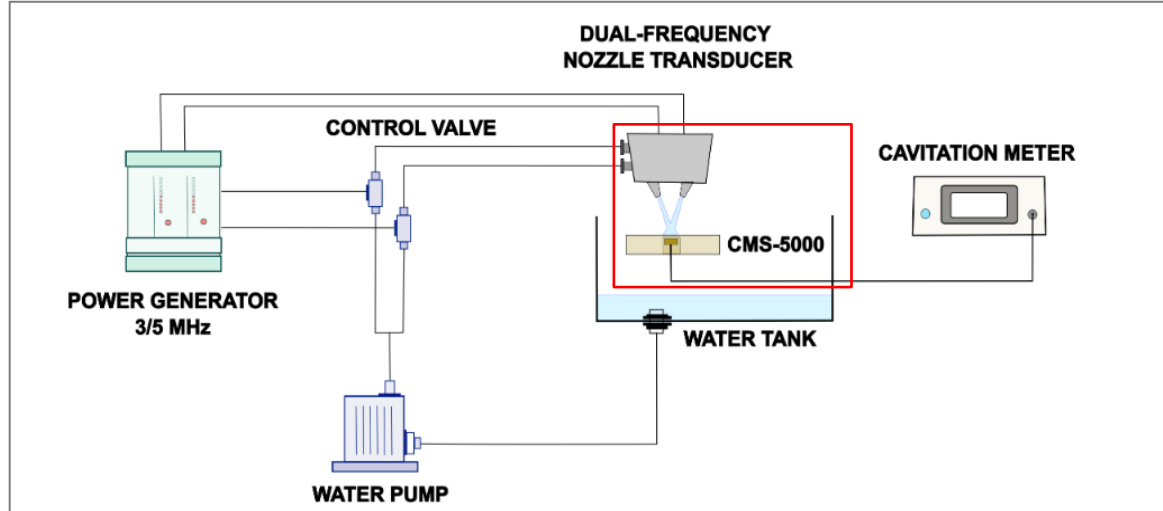
Anatomy of Acoustic Spectrum (Dual Frequency)



$$F_{\text{IMD}} = |m \cdot F01 \pm n \cdot F02|$$

EX: $F01=3$ MHz & $F02=5$ MHz,
If $n=1$ & $m=1$, then $F_{\text{IMD}}=8$ MHz

Measurement Set Up



Power generator: 3 MHz, Max Power 18 W; 5 MHz, Max Power 18 W.
Distance transducer-sensor: 17 mm.
Flow Rate: 1 LPM per nozzle.

Two-Step Approach

1. Determine the “damage free” threshold by correlating P_t with defect analysis
2. Optimize particle removal by maximizing P_s while keeping P_t below damage threshold

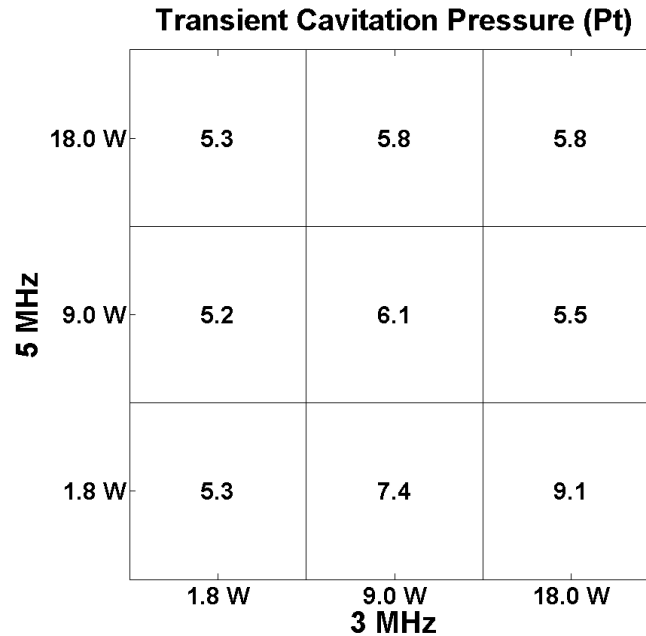


Two-Step Approach

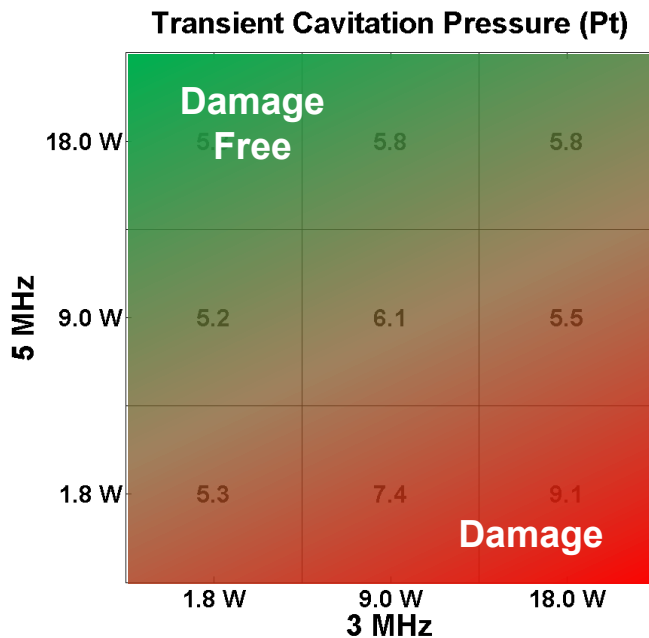
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Determine Damage Threshold



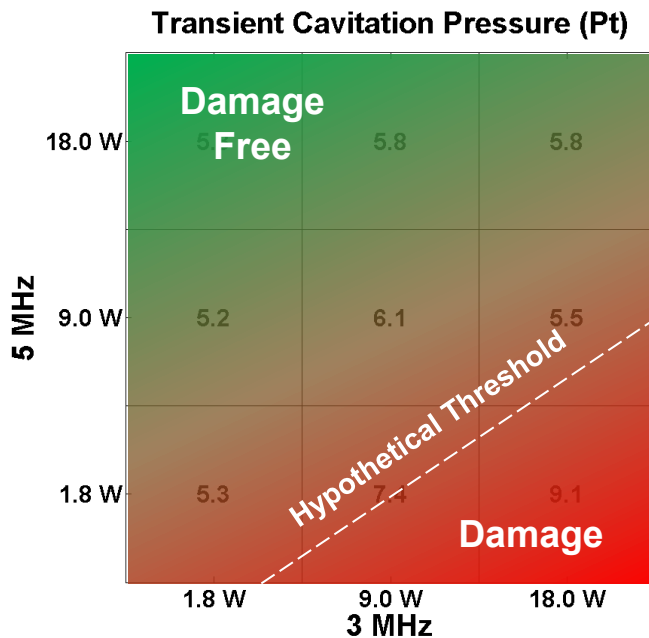
Determine Damage Threshold



Courtesy of Micron



Determine Damage Threshold



Courtesy of Micron



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Determine Particle Removal Threshold

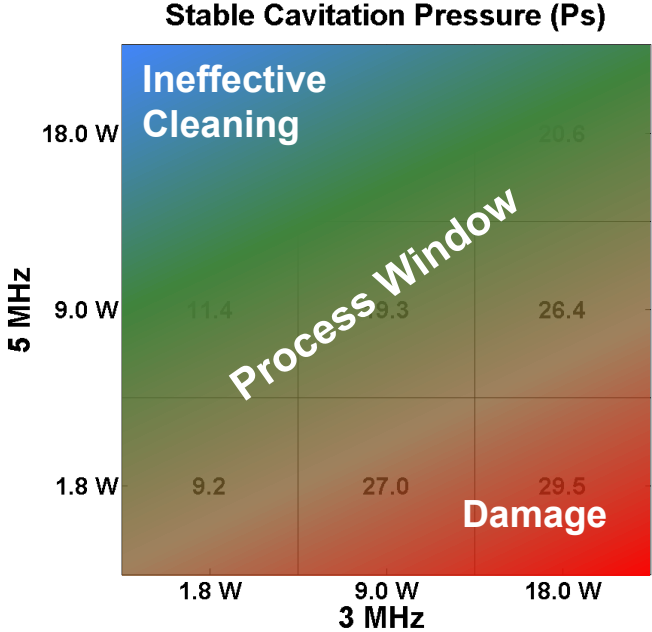
Stable Cavitation Pressure (Ps)

5 MHz	18.0 W	13.2	19.2	20.6
	9.0 W	11.4	19.3	26.4
	1.8 W	9.2	27.0	29.5
		1.8 W	9.0 W	18.0 W

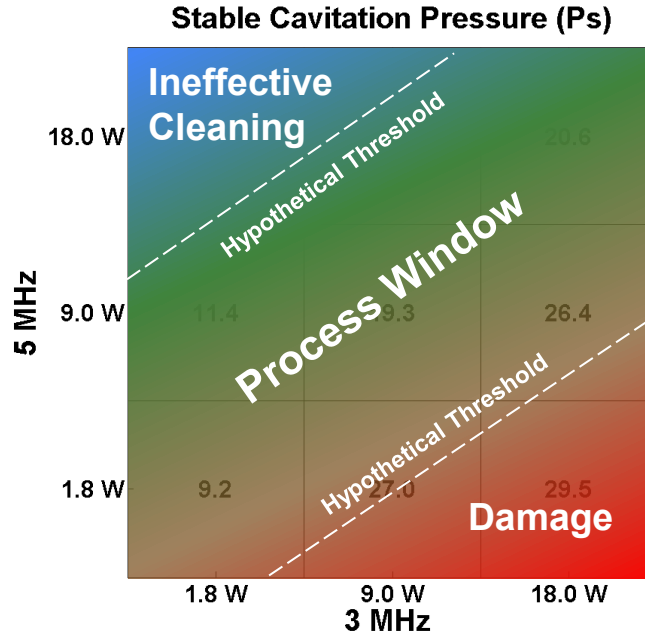
3 MHz



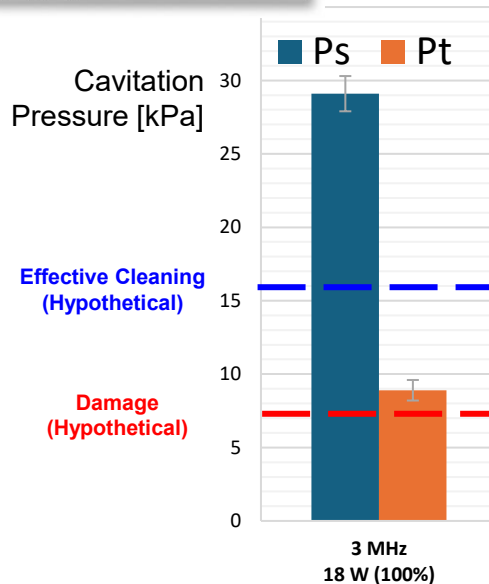
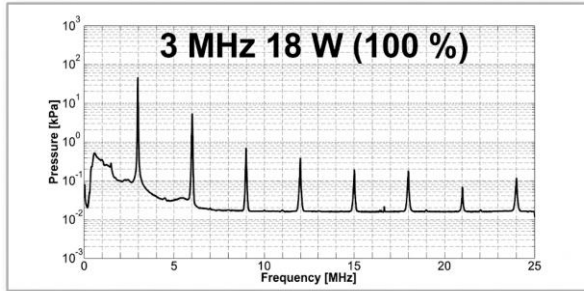
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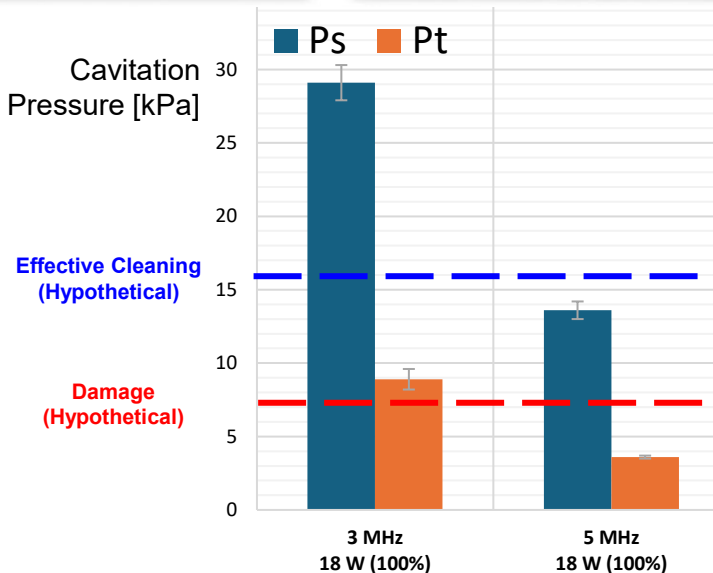
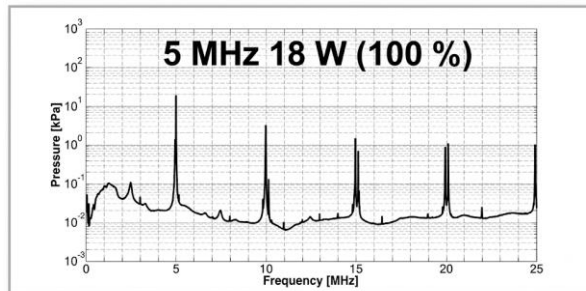
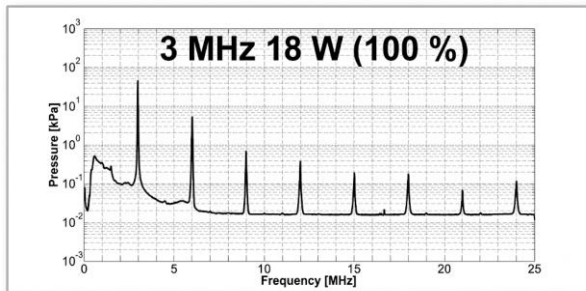


Cavitation Pressure at Different Frequencies



3 MHz cleans quickly but induces damage

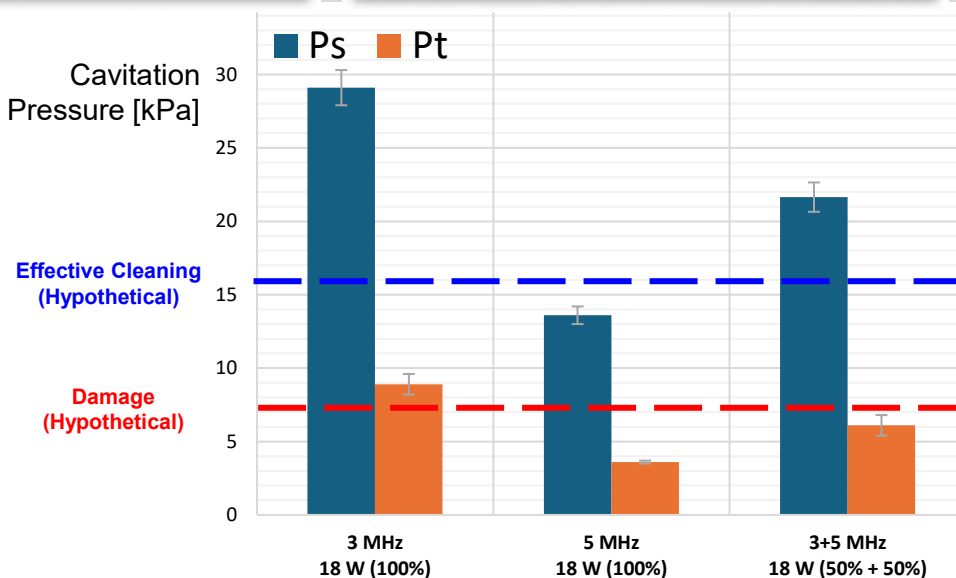
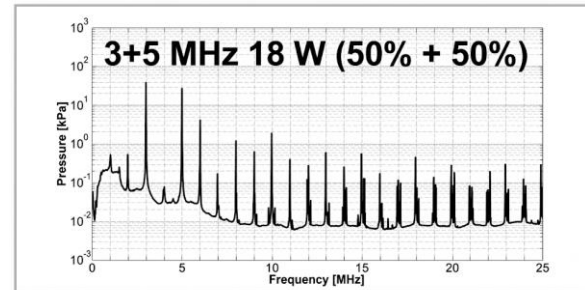
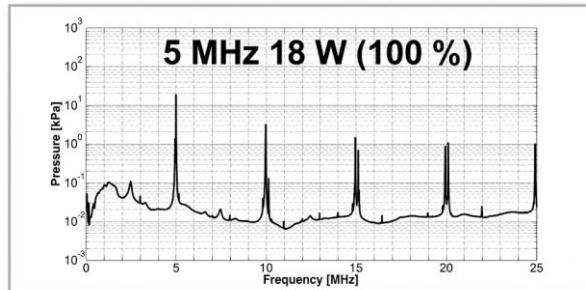
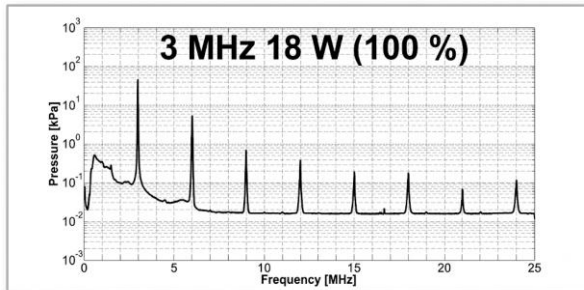
Cavitation Pressure at Different Frequencies



3 MHz cleans quickly but induces damage

5 MHz avoids damage but is ineffective with cleaning

Cavitation Pressure at Different Frequencies

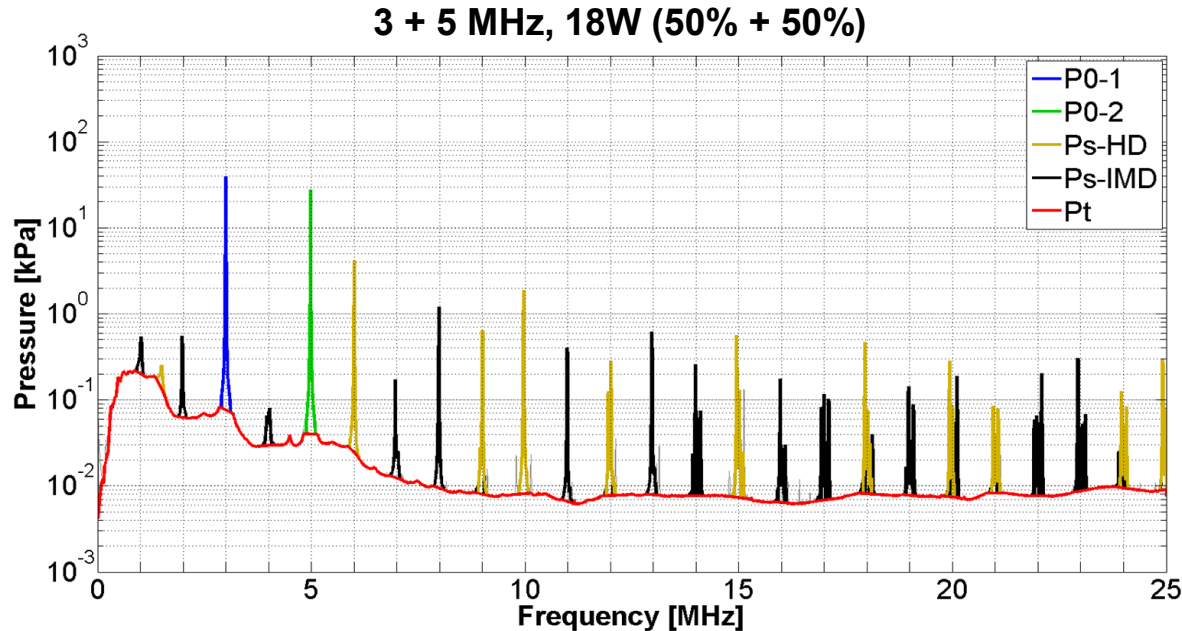


3 MHz cleans quickly but induces damage

5 MHz avoids damage but is ineffective with cleaning

Can 3+5 MHz Improve Cleaning while Avoiding Damage?

Non-linear Intermodulation Distortion from Mixing Frequencies



Ps-HD: Stable Cavitation due to Harmonic Distortion.

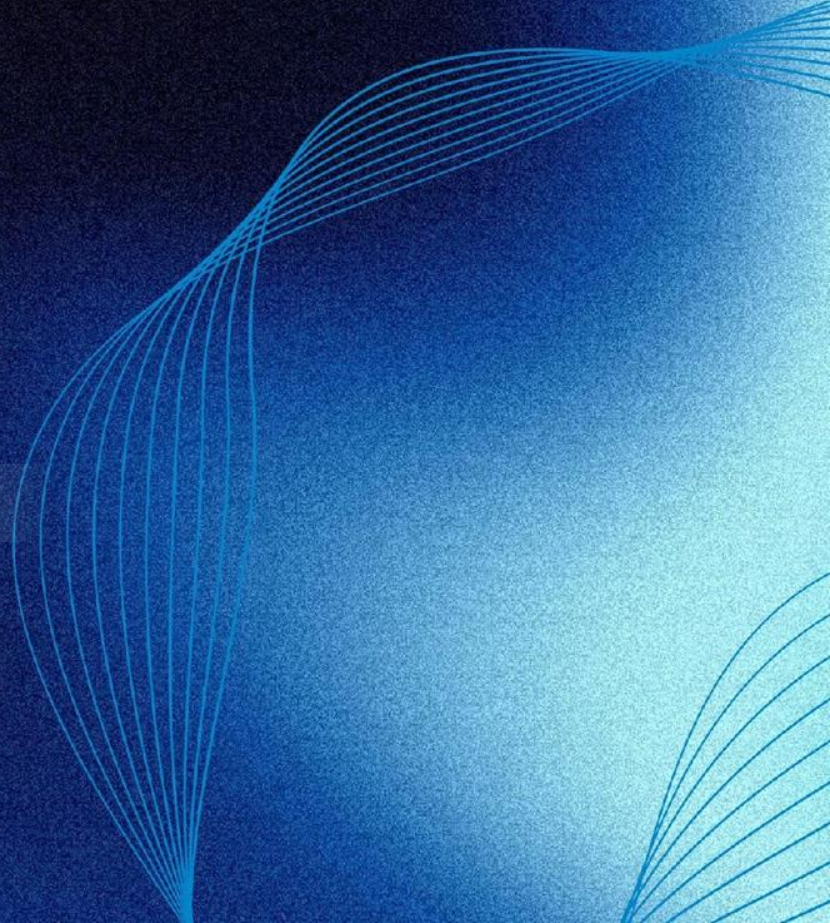
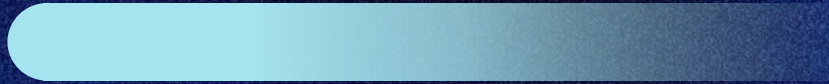
Ps-IMD: Stable Cavitation due to Non-Linear InterModulation Distortion.

A novel quantitative measurement was presented to optimize the cleaning process window

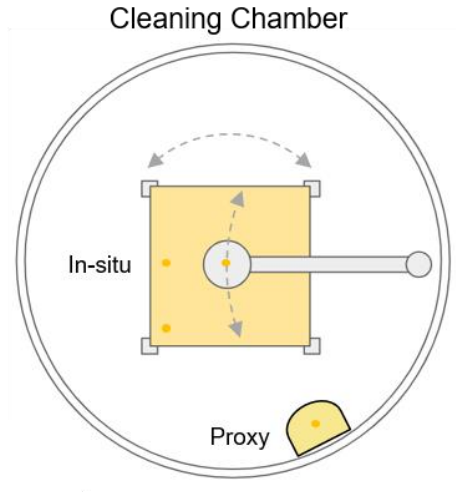
Future areas to evaluate:

- Selection of frequency combinations (i.e., higher frequencies, triple frequencies)
- Optimization of power combinations for F01 and F02
- Characterizing how other process variables (e.g., gas, temp, chemistries, fluid dynamics) influence IMD
- Direct correlation with cleaning verification (e.g., damage and particle removal)

BACKUP



In-situ Mask Sensor Array & Proxy Sensor



MSA-5000
Wireless Mask Sensor Array (In-situ)



CMS-5000 & MCT-1x00
Cavitation Monitoring Sensor (Proxy)

MSA-5000 provides in-situ measurements to correlate with cleaning
CMS-5000 enables monitoring of the transducer output